

# Mikhail Rudenko

## List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/2016520/publications.pdf>

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9  
papers

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citations

2258059

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2272923

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#	ARTICLE	IF	CITATIONS
1	On temperature and flux dependence of isotropic silicon etching in inductively coupled SF <sub>6</sub> plasma. <i>Vacuum</i> , 2022, 204, 111326.	3.5	0
2	Numerical Simulation of Cryogenic Etching: Model with Delayed Desorption. <i>Russian Microelectronics</i> , 2021, 50, 54-62.	0.5	3
3	Monte Carlo Simulation of Defects of a Trench Profile in the Process of Deep Reactive Ion Etching of Silicon. <i>Russian Microelectronics</i> , 2019, 48, 157-166.	0.5	4
4	Barrier-injection transit-time diodes and transistors for terahertz generation and detection. , 2019, , .		0
5	Sidewall defects in deep cryogenic Si etching in SF <sub>6</sub> /O <sub>2</sub> plasma: a numerical simulation. , 2019, , .		0
6	Analytic Model of Transit-Time Diodes and Transistors for the Generation and Detection of THz Radiation. <i>Russian Microelectronics</i> , 2018, 47, 290-298.	0.5	2
7	Plasma Instability of 2D Electrons in a Field Effect Transistor with a Partly Gated Channel. <i>International Journal of High Speed Electronics and Systems</i> , 2016, 25, 1640015.	0.7	12
8	Single-electron solitons in magnetic field. <i>Proceedings of SPIE</i> , 2016, , .	0.8	0
9	Instrumented wafer as a Langmuir multiprobe tool for lateral plasma homogeneity measurements in processing plasma reactors. , 2013, , .		0